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Applicant: Bohn et al.

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U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
LV	4,092,445	May 30, 1978	Tsuzuki et al.			
	5,139,624	Aug. 18, 1992	Searson et al.			
	5,206,523	Apr. 27, 1993	Goesele et al.			
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						Yes	No

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LV	T. Monguchi, H. Fujioka, K. Ono, Y. Baba, M. Oshima, "Effects of Wet Etching on Photoluminescence of Porous Silicon", <i>Journal of The Electrochemical Society</i> , Vol. 147, No. 2, 2000, pp. 602-605.
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Examiner LAN VINH

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